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Microbeam analysis — Electron probe microanalysis — Guidelines for qualitative point analysis by wavelength dispersive X-ray spectrometry

Analyse par microfaisceaux — Analyse par microsonde électronique (Microsonde de Castaing) — Lignes directrices pour l'analyse qualitative ponctuelle par spectrométrie de rayons X à dispersion de longueur d'onde (WDX)

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Foreword

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The committee responsible for this document is ISO/TC 202, *Microbeam analysis*, Subcommittee SC 2, *Electron probe microanalysis*.

This second edition cancels and replaces the first edition (ISO 17470:2004), of which it constitutes a minor revision.

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Introduction

Electron probe microanalysis is used to qualitatively identify the elements present in a specimen on a micrometric scale. It is necessary to specify the measurement conditions and identification method in order to avoid reporting erroneous or inconsistent results.

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